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<b>Substitute for form 1449A/PTO</b>  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (Use as many sheets as necessary)				Application Number		10/785,254		
				Filing Date		2/23/2004		
				First Named Inventor:		Linyong Pang		
				Examiner: Sun J. Lin		GROUP: 2825		
Sheet	1	of	1	Attorney Docket Number		NTI-849		
<b>U.S. PATENT DOCUMENTS</b>								
Examiner Initials*	Cited No. <sup>1</sup>	Document Number Number - Kind Code <sup>2(f/known)</sup>		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Passages or Figures Appear		
JSL	A01	US-6,289,499	B1	09/2001	Rieger et al.	_____		
JSL	A02	US-2002/0164065	A1	11/2002	Cai et al.	_____		
JSL	A03	US-2002/0194576	A1	12/2002	Toyama	_____		
<b>FOREIGN PATENT DOCUMENTS</b>								
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document Cntry Code <sup>3</sup> Number <sup>4</sup> Kind Code <sup>5 (f/known)</sup>			Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Passages or Figures Appear	T <sup>6</sup>
JSL	A04	WO	01/65317	A2	09/2001	Spence	_____	
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>								
JSL	Lu et al. "Application of Simulation Based Defect Printability Analysis for Mask Qualification Control," Proceedings of the SPIE, Vol. 5038, February 2003, pg. 33-40							
JSL	Pang et al. "Simulation-based Defect Printability Analysis on Alternating Phase Shifting Masks for 193 nm Lithography," Proceedings of the SPIE, Vol. 4889, October 2002, pg. 947-954							
JSL	Randall et al. "Variable Threshold Resist Models for Lithography Simulation," Proceedings of the SPIE, Vol. 3679, March 1999, pg. 176-182							
EXAMINER SIGNATURE: <u>James Sun Lin</u>					DATE CONSIDERED: <u>11-07-05</u>			

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. 1 Applicant's unique citation designation number (optional). 2 See Kinds Codes of USPTO Patent Documents at [www.uspto.gov](http://www.uspto.gov) or MPEP 901.04. 3 Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). 4 For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. 5 Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. 6 Applicant is to place a check mark here if English language Translation is attached.

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